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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of : Attorney Docket No. OKI.614
Yasuhiro Yamamoto et al. : Examiner: Young, Christopher G
Application No.: 10/761,215 : Group Art Unit: 1756
Filed: January 22, 2004 : Confirmation No. 2755
For: FLARE MEASURING MASK AND FLARE MEASURING METHOD OF SEMICONDUCTOR
ALIGNER

LETTER REQUESTING ACKNOWLEDGEMENT OF CLAIM OF PRIORITY

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Date: November 21, 2006

Sir:

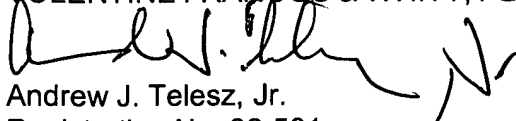
A certified copy of Japanese priority application no. 2003-371747 was filed on November 13, 2006, in connection with the above identified application. Japanese priority application no. 2003-371747 has been entered into the image file wrapper of the present application at the U.S. Patent Office website.

The Examiner is respectfully requested to confirm that the Claim for Priority under 35 U.S.C. 119 is thus complete in the present application.

In the event that there are any outstanding matters remaining in the present application, please contact Andrew J. Telesz, Jr. (Reg. No. 33,581) at (571) 283-0720 in the Washington, D.C. area, to discuss these matters.

Respectfully submitted,

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